



Study of Thermal Diffusivity of Dielectric-Metal Interfaces at Low Temperatures

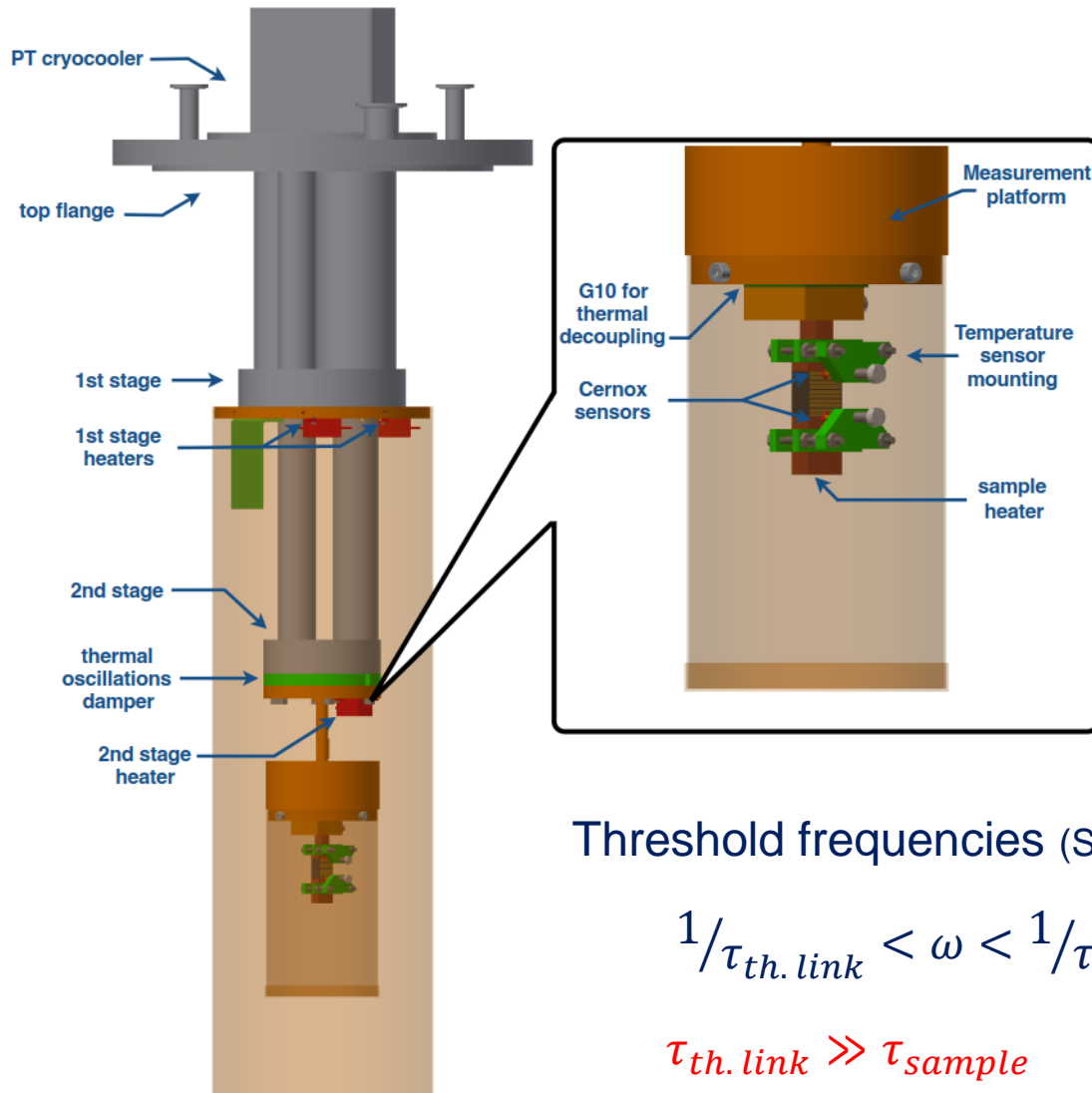
T. Koettig, P. Borges de Sousa, J. Golm, J. Liberadzka, J. Bremer

CERN, TE/CRG-CI Central Cryogenic Laboratory

Content

- Introduction to the test set-up
- Method applied and samples
- Measurements and numerical modelling
 - Copper as reference sample
 - Dielectric to metal interfaces
 - Indium or titanium on sapphire
 - SC cable via epoxy impregnation
- Comparison: amplitude vs. τ - method
- Conclusion

Thermal conductivity / diffusivity set-up



Features:

- 3 temperature sensors calibrated to each other + offset compensation
- Stepwise change of platform temperature 1 K - 2 K
- ΔT on sample 0.2 K to 0.3 K
- Passive thermal attenuator between cryocooler and thermal platform

Threshold frequencies (Stewart *et al.*, Rev. Sci. Instrum. 54, 1 (1983):

$$1/\tau_{th. link} < \omega < 1/\tau_{sample} \quad \text{with} \quad \tau = RC = \frac{C}{\Lambda}$$

$$\tau_{th. link} \gg \tau_{sample}$$

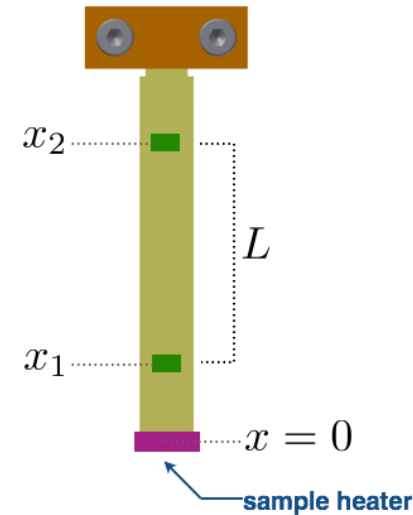
Measurement methodology I

Thermal conductivity: $\lambda = \frac{\dot{Q} \cdot L}{A \cdot \Delta T}$

λ - thermal conductivity
 \dot{Q} - heat load
 L - length along x
 A - cross section
 ΔT - temperature difference

Thermal diffusivity: $D = \frac{\lambda}{c \cdot \rho}$

D - thermal diffusivity
 c - heat capacity
 ρ - density



$$\frac{\delta T}{\delta t} = D \cdot \frac{\delta^2 T}{\delta x^2} \Rightarrow T(L, t) = T_0 \left(1 + e^{-\frac{L}{\mu}} \cos\left(\omega t - \frac{L}{\mu}\right) \right)$$

Phase shift method

$$\mu_{\text{phase}} = \frac{L}{\phi_0 - \phi_x}$$

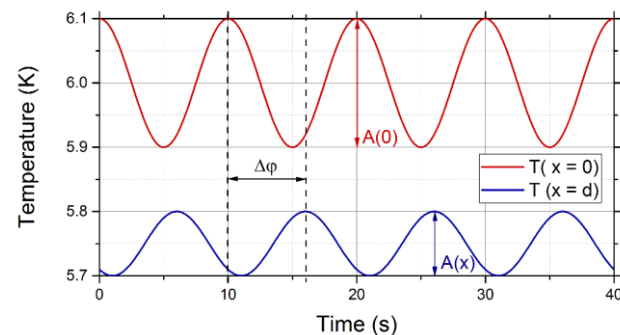
$$\phi \text{ (rad)} = \frac{\Delta t \text{ (s)} \cdot 2\pi}{\text{Period time}}$$

Amplitude method

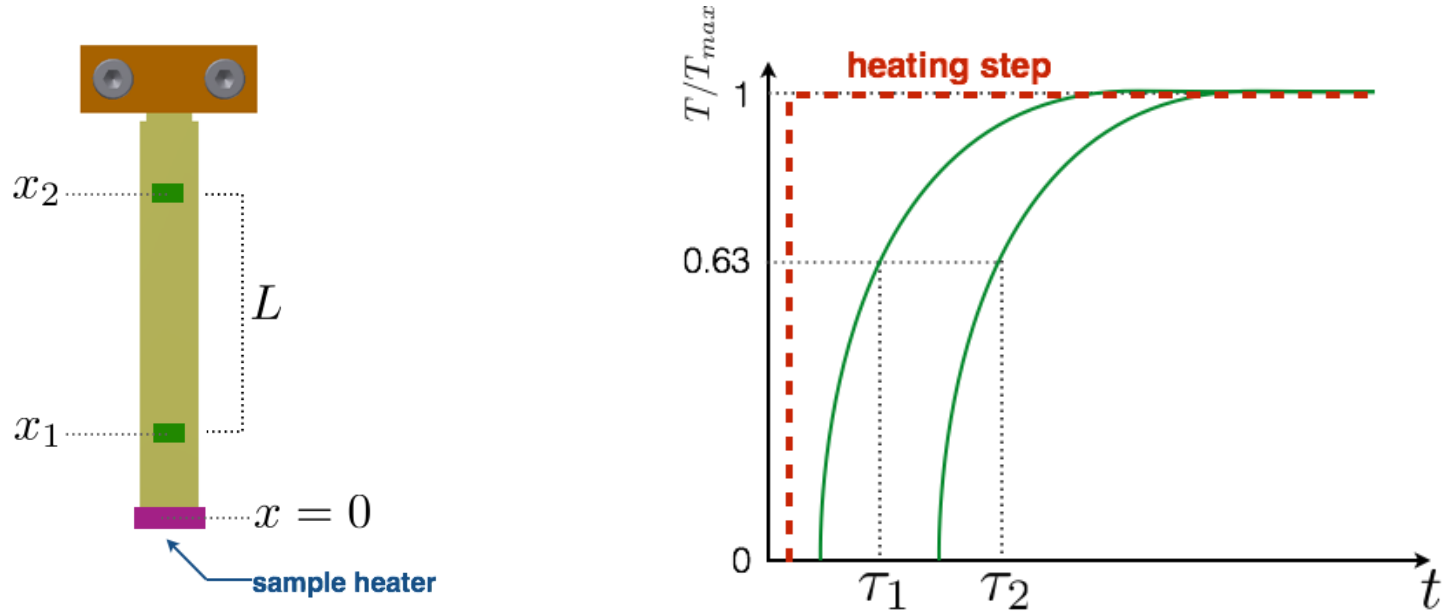
$$\mu_{\text{atten.}} = \frac{L}{\ln\left(\frac{A_0}{A_x}\right)}$$

$$D = \frac{\mu^2 \cdot \omega}{2}$$

D - thermal diffusivity in m²/s
 L - length in m
 μ - thermal diffusion length in m



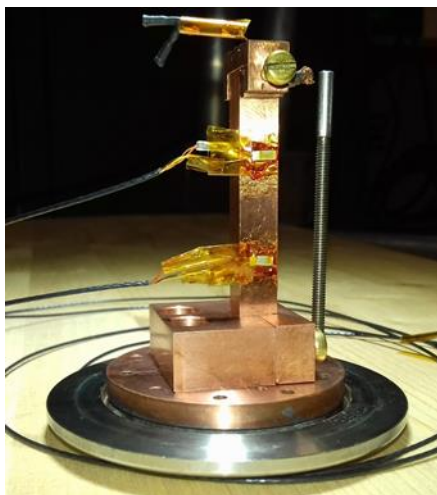
Measurement methodology II



$$\tau = R \cdot C = \frac{m \cdot c}{A/x \cdot \lambda} = \frac{x \cdot V \cdot \rho \cdot c}{A \cdot \lambda} = \frac{x}{A} \cdot \frac{V}{D} = \frac{x^2}{D}$$

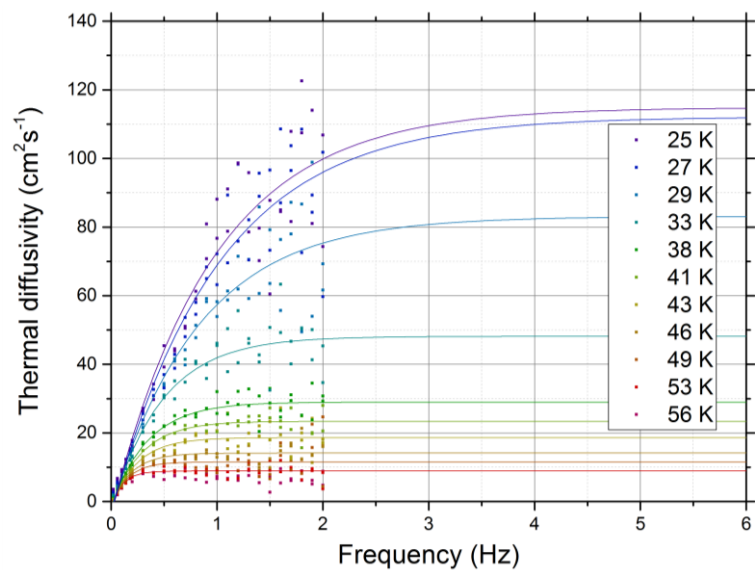
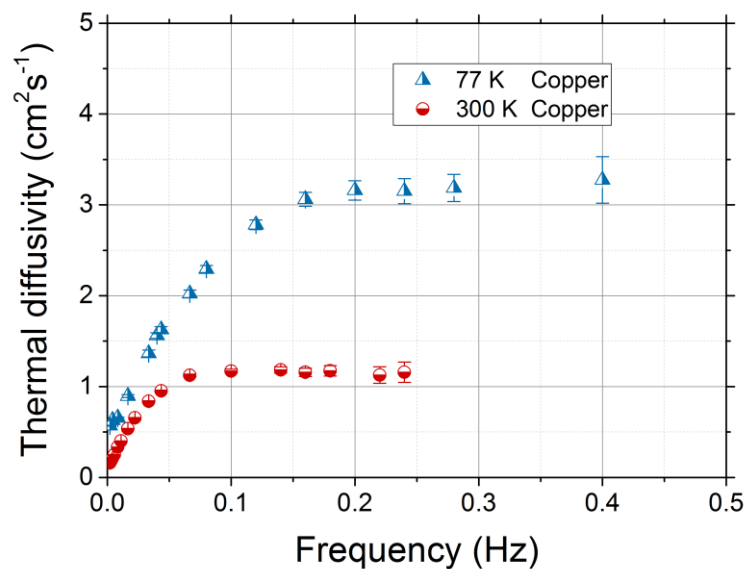
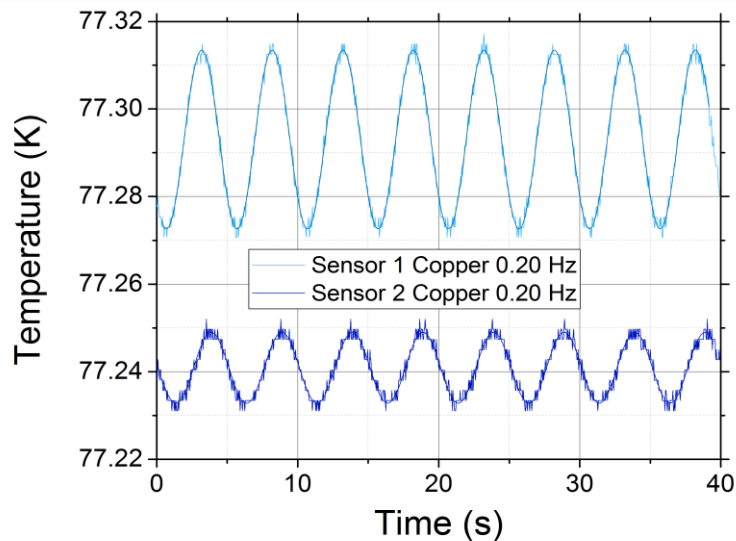
$$D^* = \frac{L^2}{\Delta\tau} \quad \tau \text{ - method}$$

Diffusivity measurements on reference sample Cu-OFHC

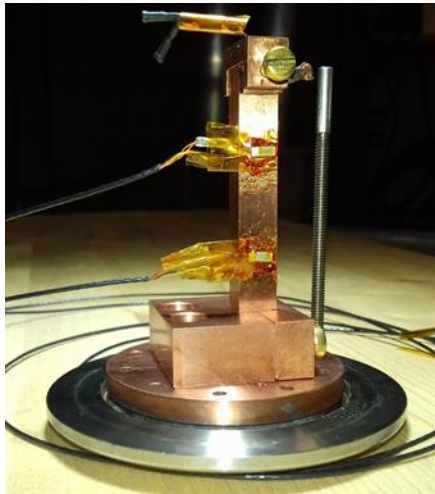


Oxygen-free
high-conductivity
(OFHC) copper

Dimensions:
 $8 \times 8 \times 50 \text{ mm}^3$

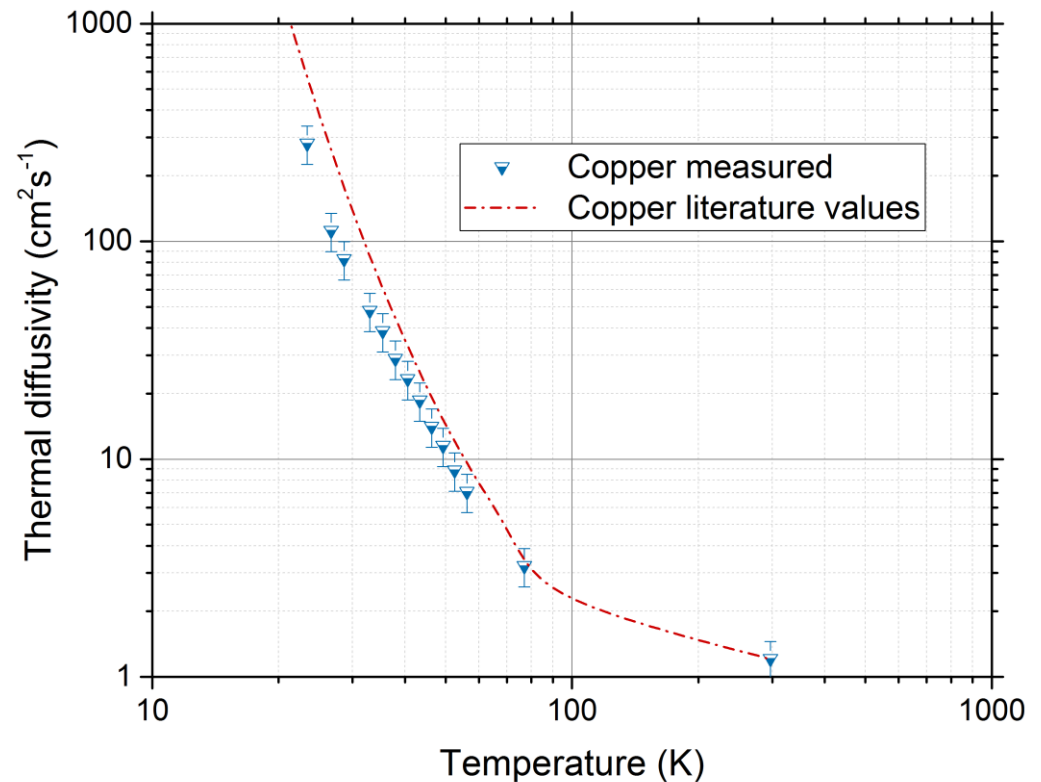


Diffusivity measurements on reference sample Cu-OFHC



$D(T)$ measured is in good agreement with literature values.

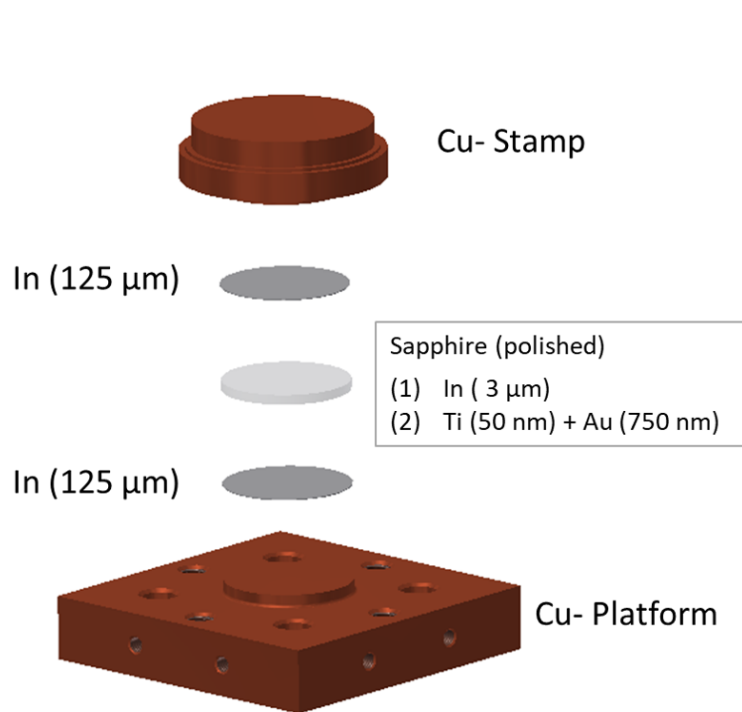
- Amplitude method can be used for more complex samples
- Samples and interfaces need to be adapted



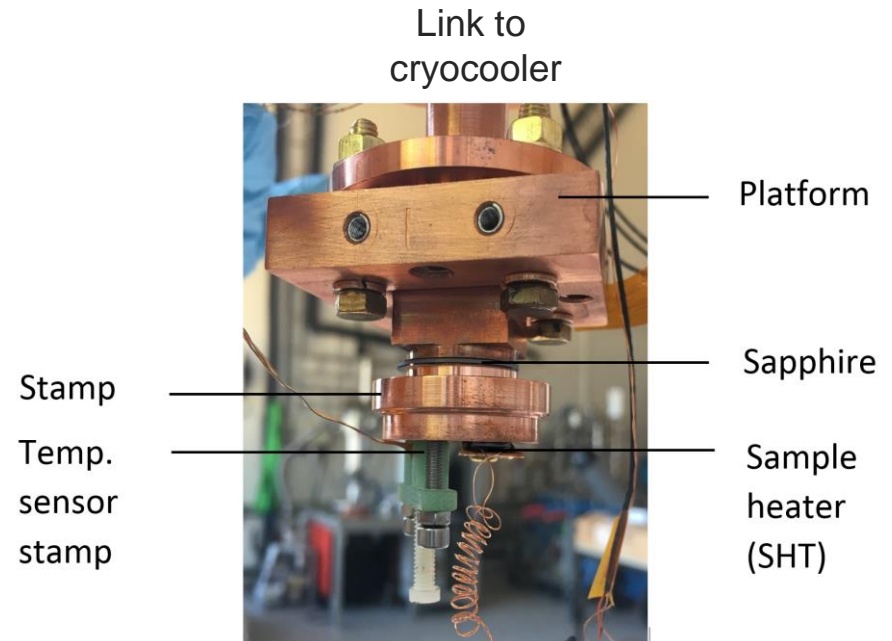
Literature data from: J. E. Jensen *et al.*, Thermal Diffusivity, Brookhaven National Laboratory Selected Cryogenic Data Notebook, Brookhaven National Laboratory (1980).

OFHC copper tested RRR~100 from th. conductivity results

Thermal diffusivity of a Cu-In- sapphire and Cu-In-Au-Ti-sapphire sandwich



See results presented by J. Liberadzka
 in her talk: E-09: 32

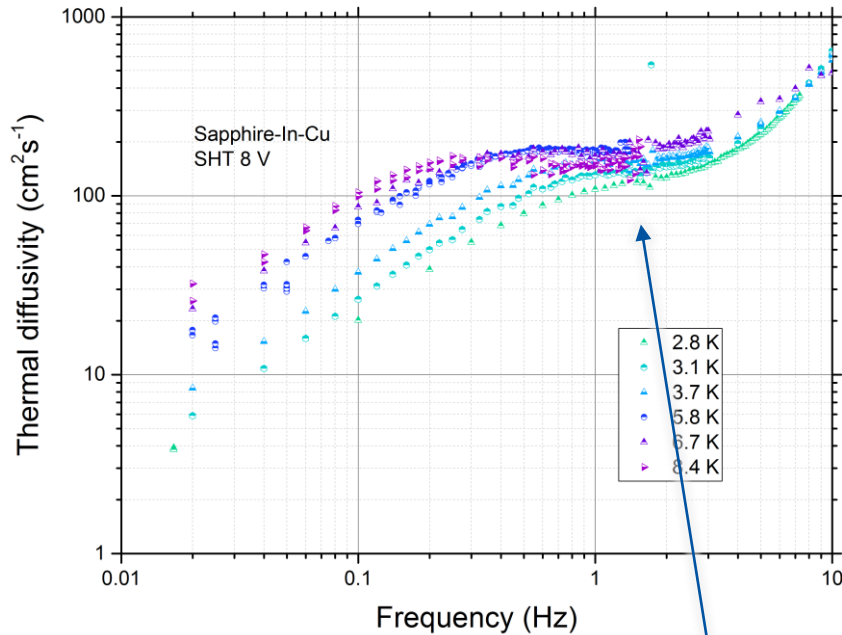


Indium sample :	Cu-In-sapphire-In-Cu
Ti-Au sample:	Cu-In-Au-Ti-sapphire-Ti-Au-In-Cu

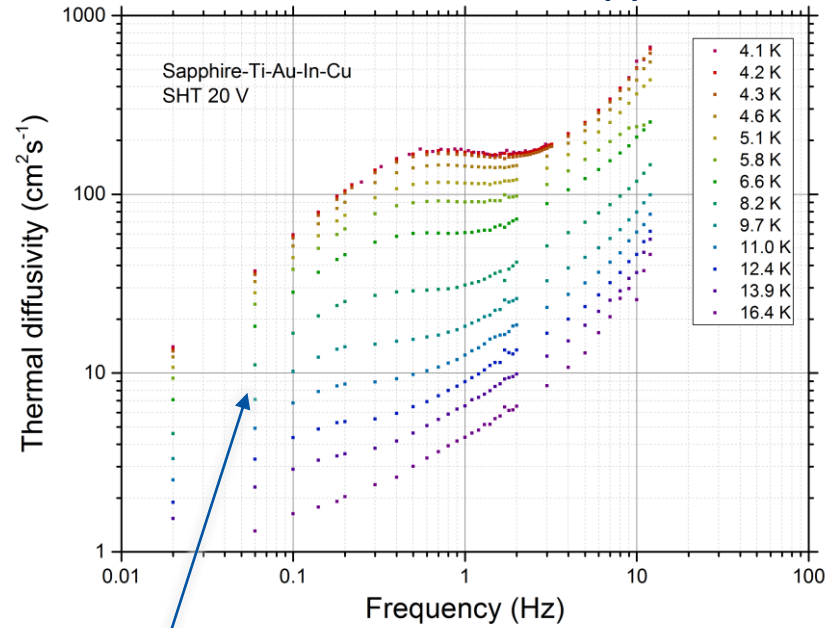
Definition of a diffusivity-like value (due to the presence of interfaces) $\Rightarrow D^*$

Thermal diffusivity of a Cu-In-sapphire and Cu-In-Au-Ti-sapphire sandwich

Cu-In-Sapphire



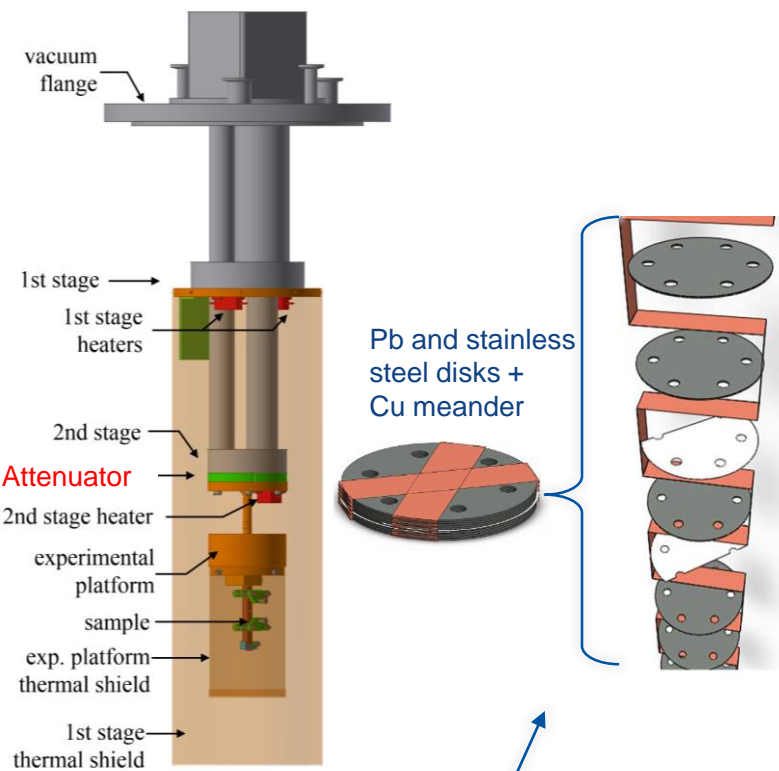
Cu-In-Au-Ti-Sapphire



Influences by the cryocooler frequency and threshold frequency are visible

There is a clever solution to attenuate the cryocooler oscillations and increase $\tau_{th.link}$

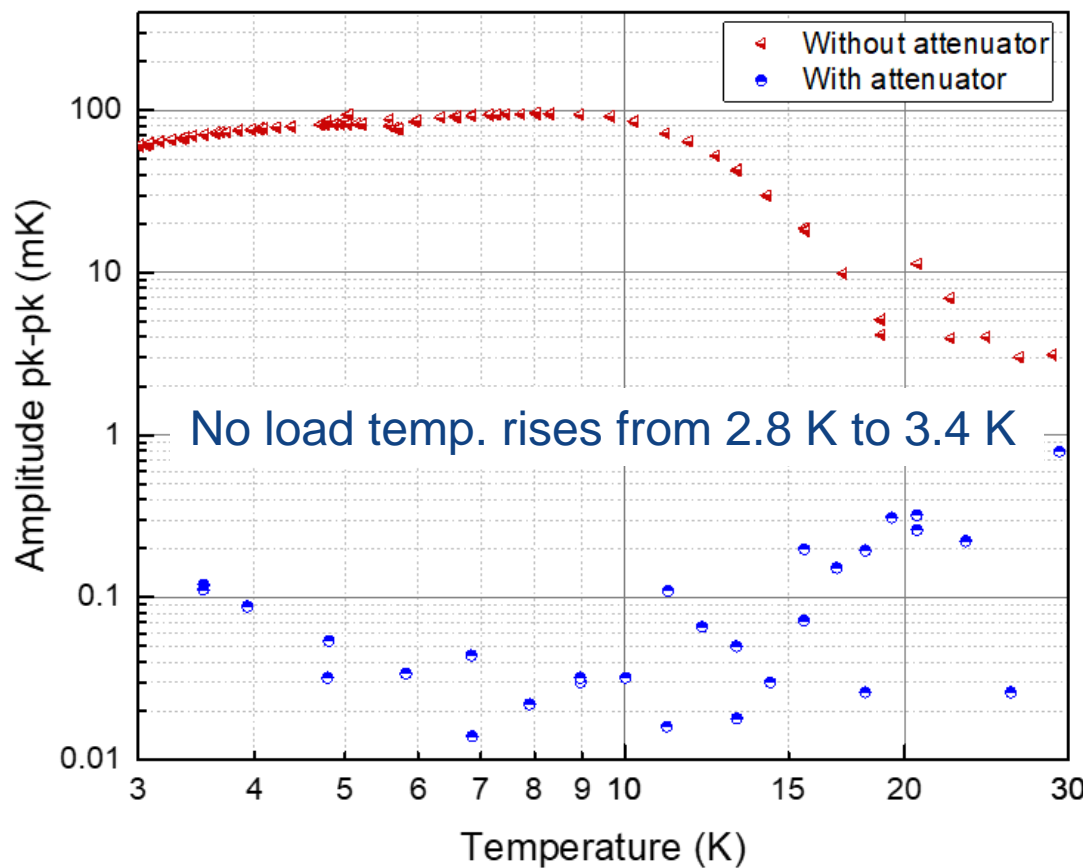
Passive thermal attenuator (G. Dubuis)



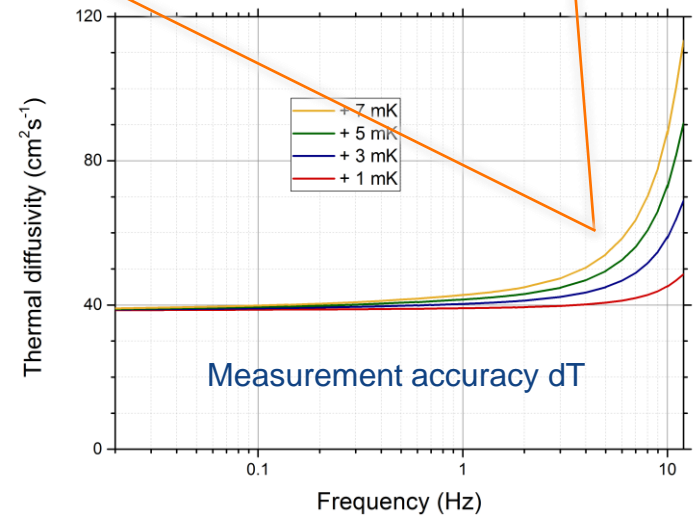
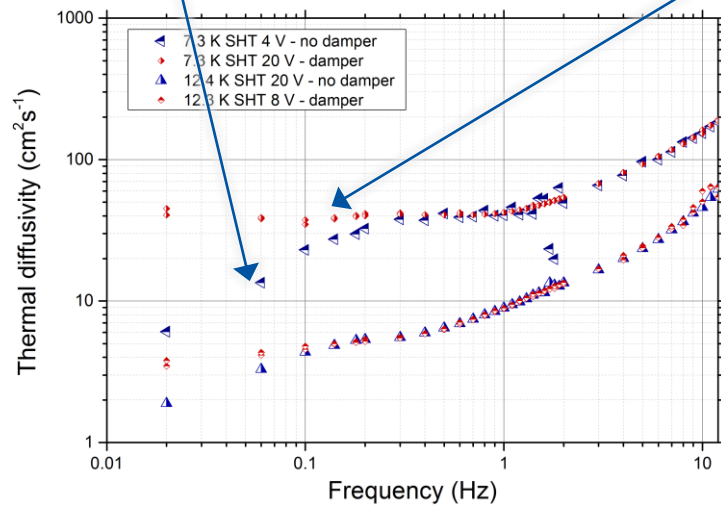
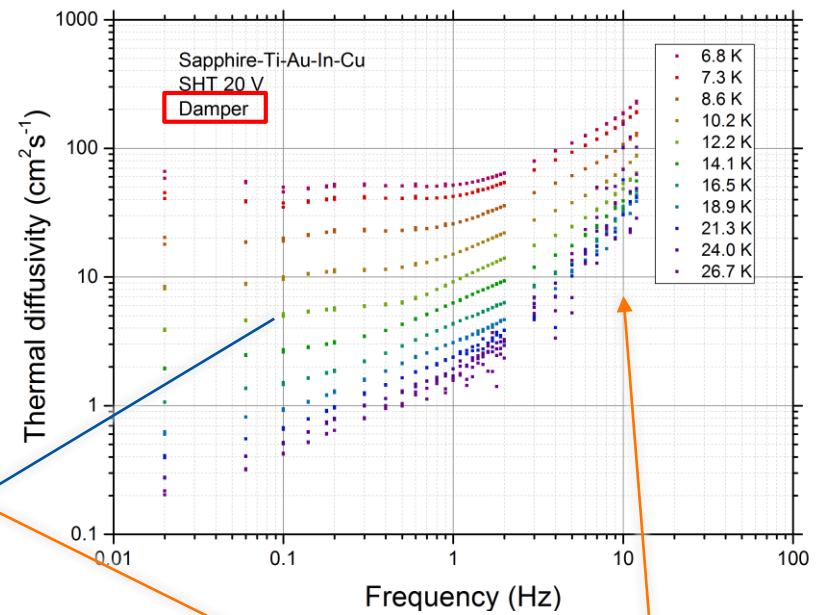
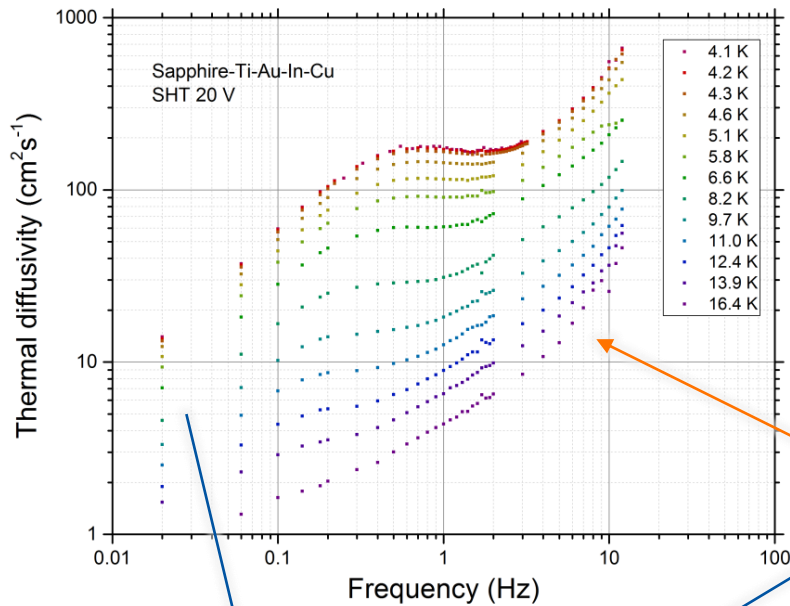
Courtesy: G. Dubuis, X. He, and I. Božovic, Sub-milliKelvin stabilization of a closed cycle cryocooler, Rev. Sci. Instrum. 85, 103902 (2014).

Our version CERN Cryolab with:

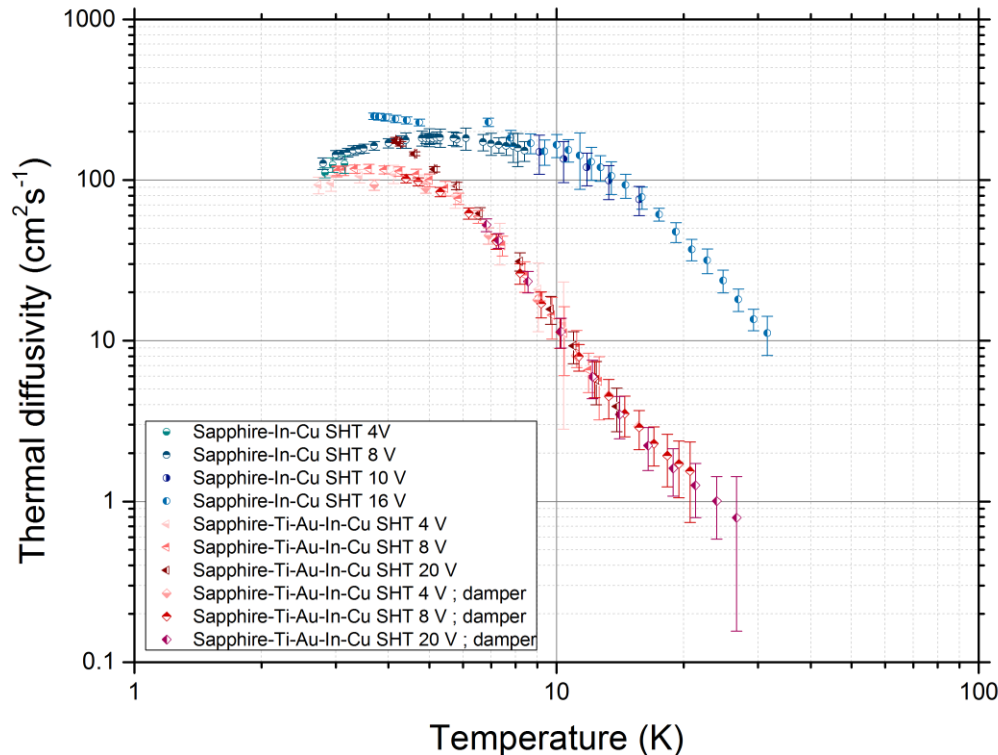
Cryocooler SHI RP-082B2 oscillations at $f_{op} = 1.725$ Hz



Thermal diffusivity of a Cu-In-sapphire and Cu-In-Au-Ti-sapphire sandwich



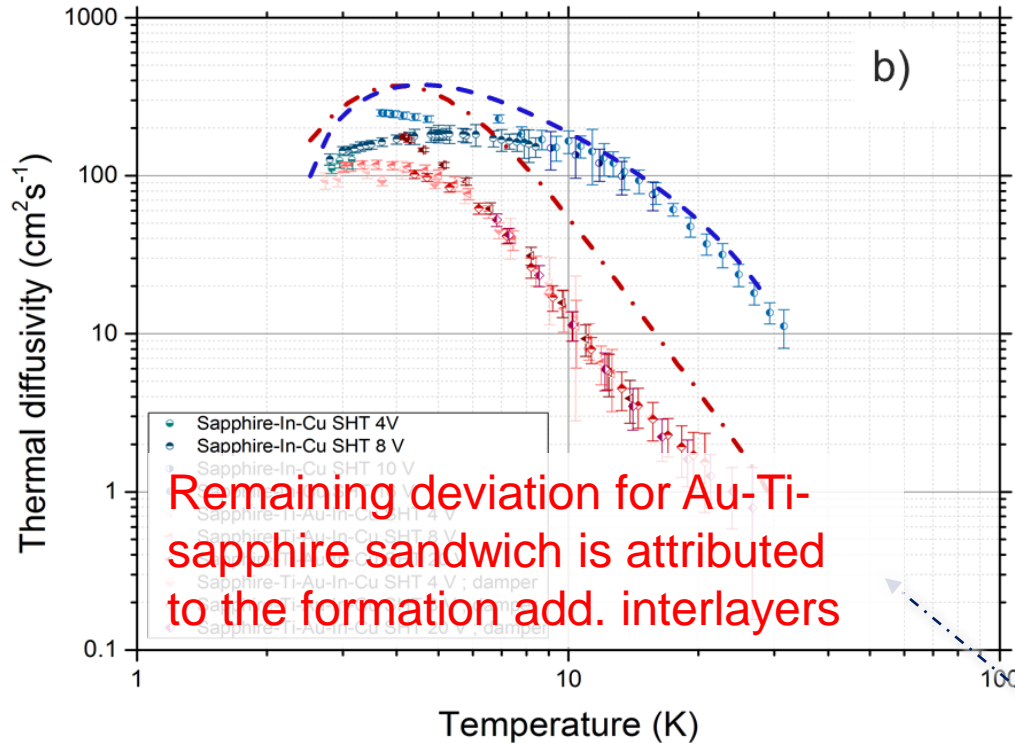
Thermal diffusivity of a Cu-In- sapphire and Cu-In-Au-Ti-sapphire sandwich



- $D^*_{\text{Cu-In-Sapphire}} > D^*_{\text{Cu-In-Au-Ti-Sapphire}}$
- $D^*_{\text{max,Cu-In-Au-Ti-Sapphire}}$ is at lower T
- Curves almost merge at about 3 K
- Cu-In-Au-Ti-Sapphire has additional interfaces \rightarrow additional thermal resistance

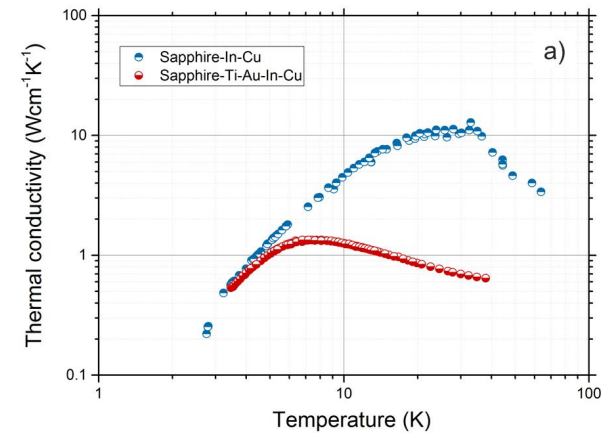
Numerical modelling of that structure =>

Thermal diffusivity of a Cu-In-sapphire and Cu-In-Au-Ti-sapphire sandwich



Numerical modelling =>

measured thermal conductivity



$$R_s = R_{sap} + R_{In} + R_{Cu} + R_{InSapIn}$$

$$R_{InSapIn} = \frac{1}{225} T^{2.5-3.0}$$

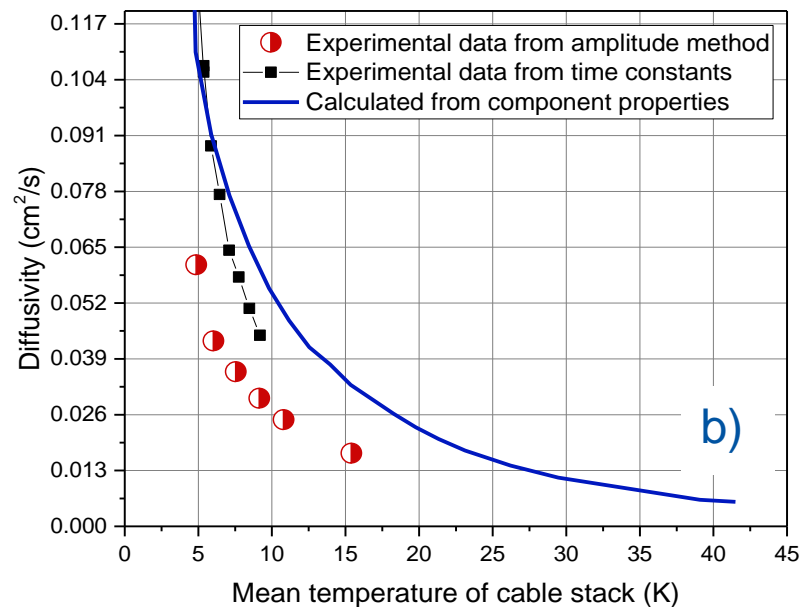
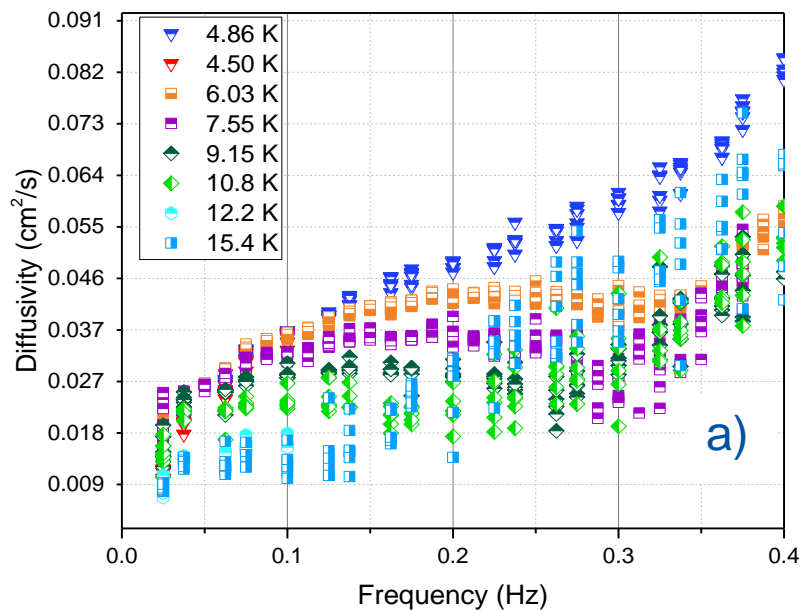
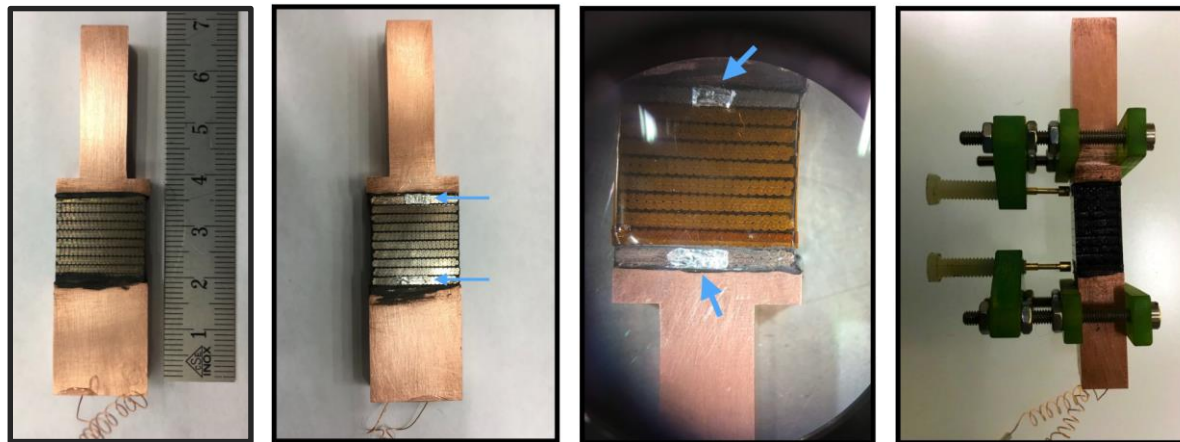
$$\text{Geometry} + c_s \cdot \rho_s = \sum_i \frac{x_i}{d} \cdot c_i \cdot \rho_i$$

$$D^* = \frac{d}{A \cdot R_s \cdot c_s \cdot \rho_s}$$

Comparing methods: amplitude attenuation vs. step function

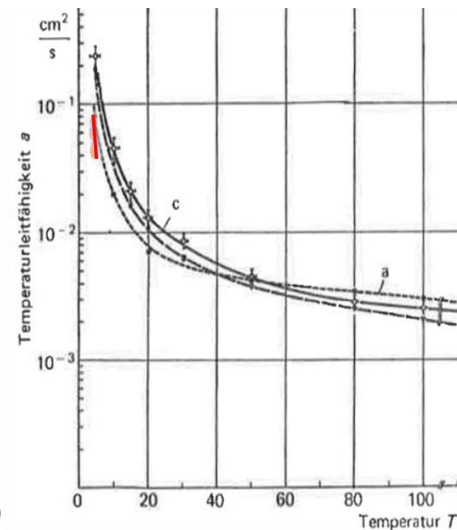
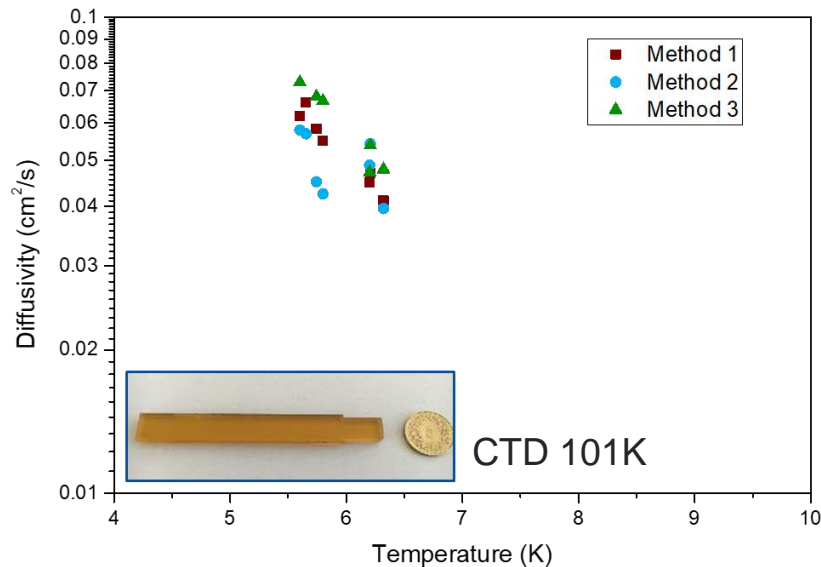
Sample:

Nb₃Sn Rutherford type cable stack of 11 T dipole, fully impregnated



Conclusion

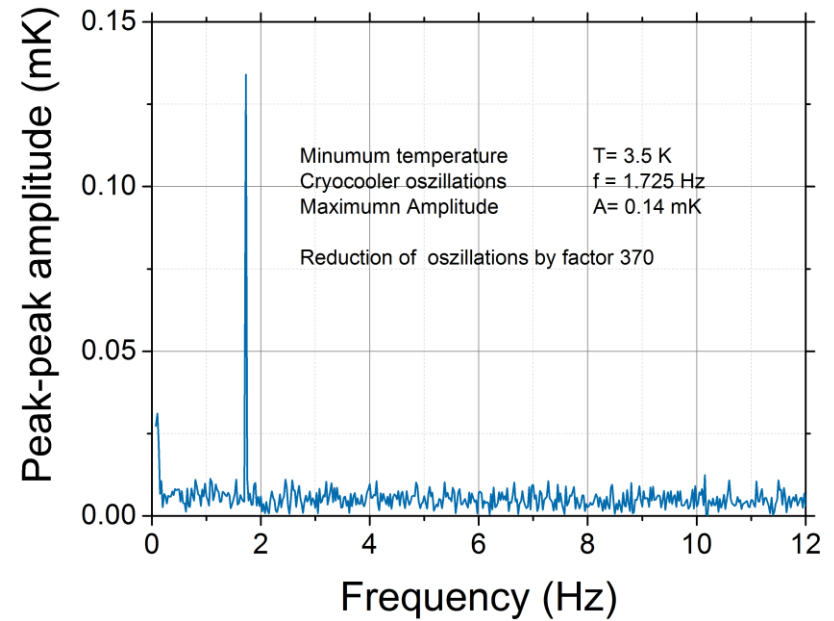
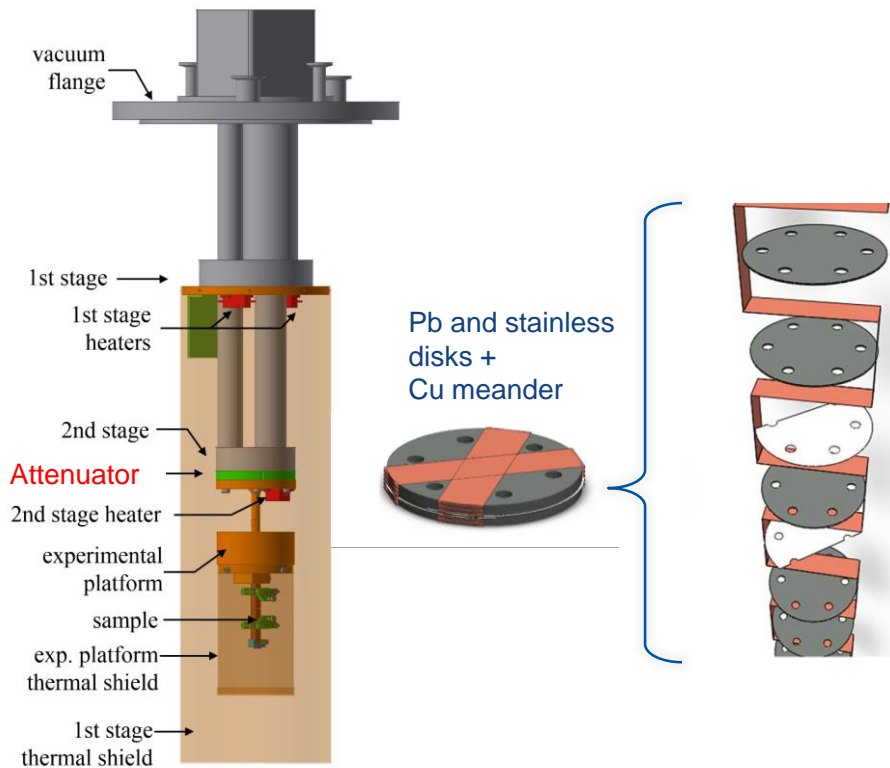
- ✓ Evaluation of measurement methods
- ✓ OFHC-copper measurement and comparison with literature values
- ✓ Inhomogenous stackd with dielectric-metal interfaces
- ✓ Comparison of methods for bulk samples
- ✓ Amplitude attenuation and step methods seem to be complementary





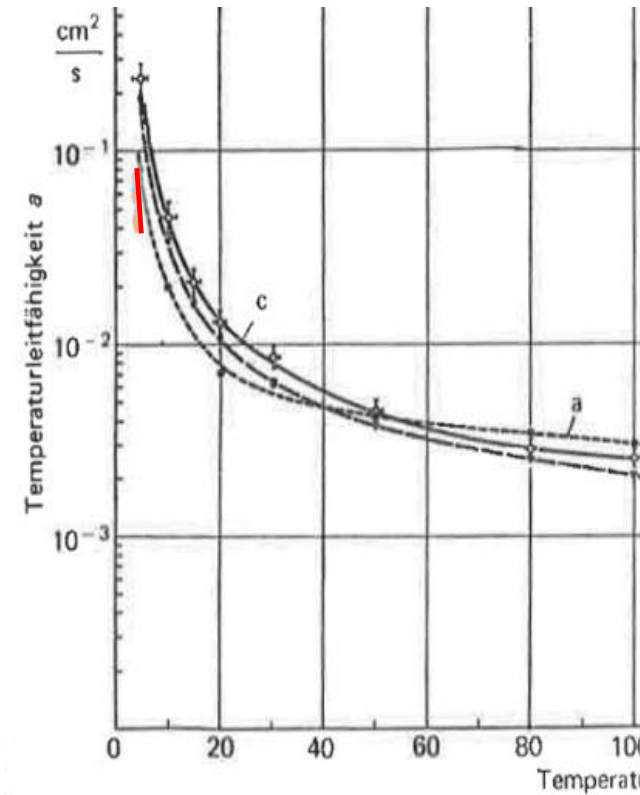
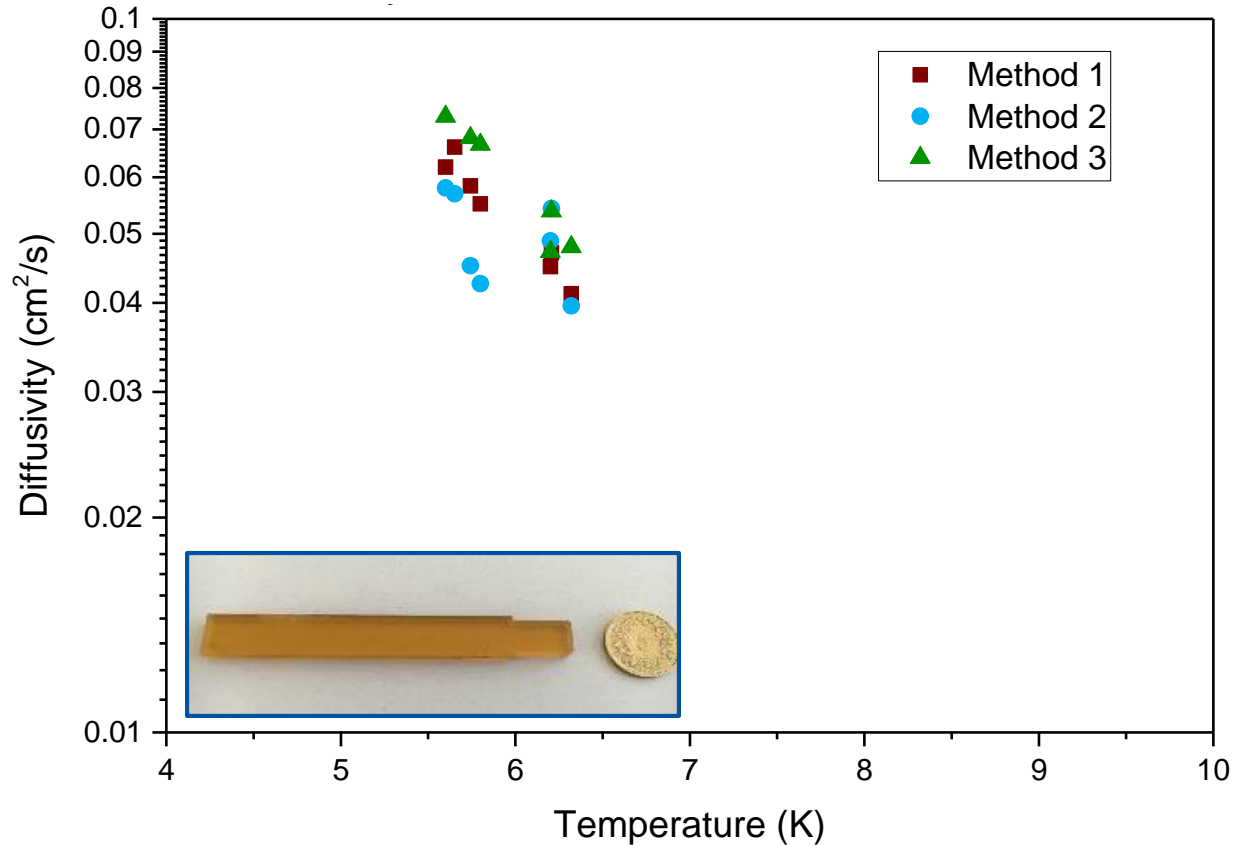
www.cern.ch

Passive thermal attenuator



Courtesy: G. Dubuis, X. He, and I. Božovic, Sub-milliKelvin stabilization of a closed cycle cryocooler, Rev. Sci. Instrum. 85, 103902 (2014).

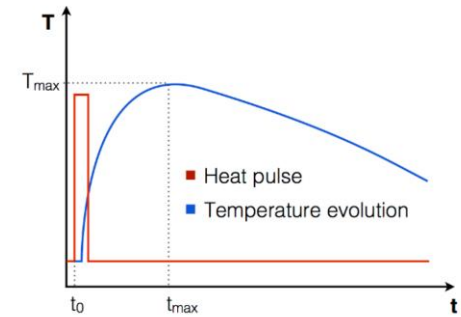
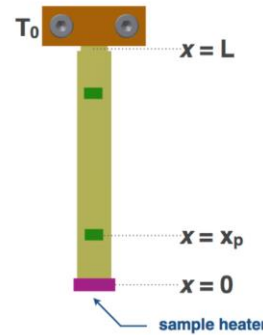
HiLumi LHC₁₁ T Nb₃Sn Dipole => CTD-101K bulk epoxy sample



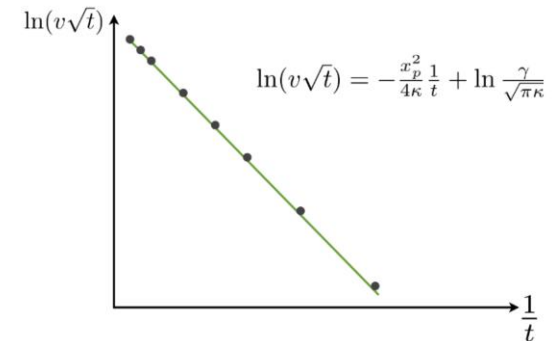
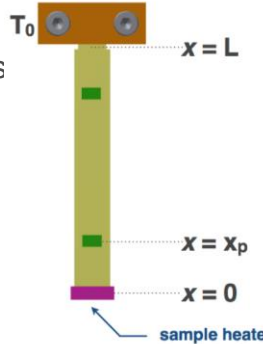
From: Frey, H. and Haefer, R. A., *Tiefemperaturtechnologie*

Further diffusivity measurement methods

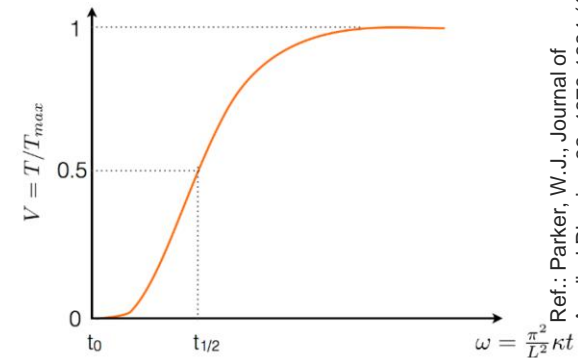
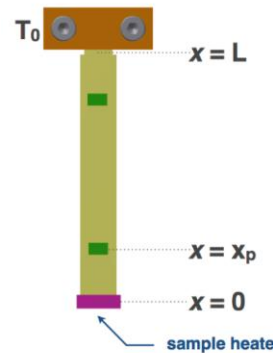
- Pulse:** $\kappa = \frac{x_p^2}{2t_{max}}$
 - x_p is the distance between the heater and the sensor
 - t_{max} is the time at which the temperature at x_p reaches its maximum



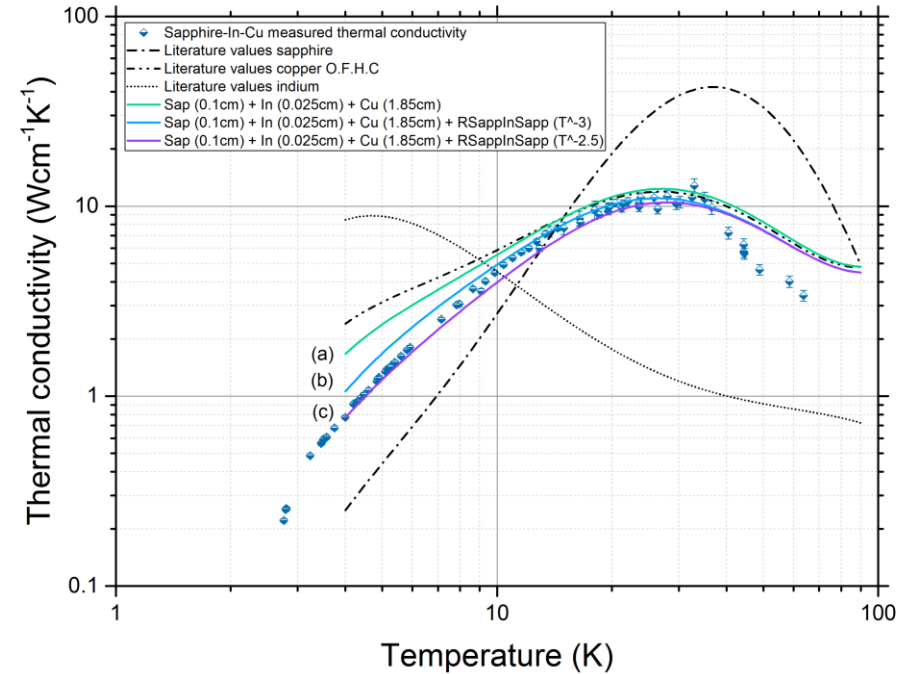
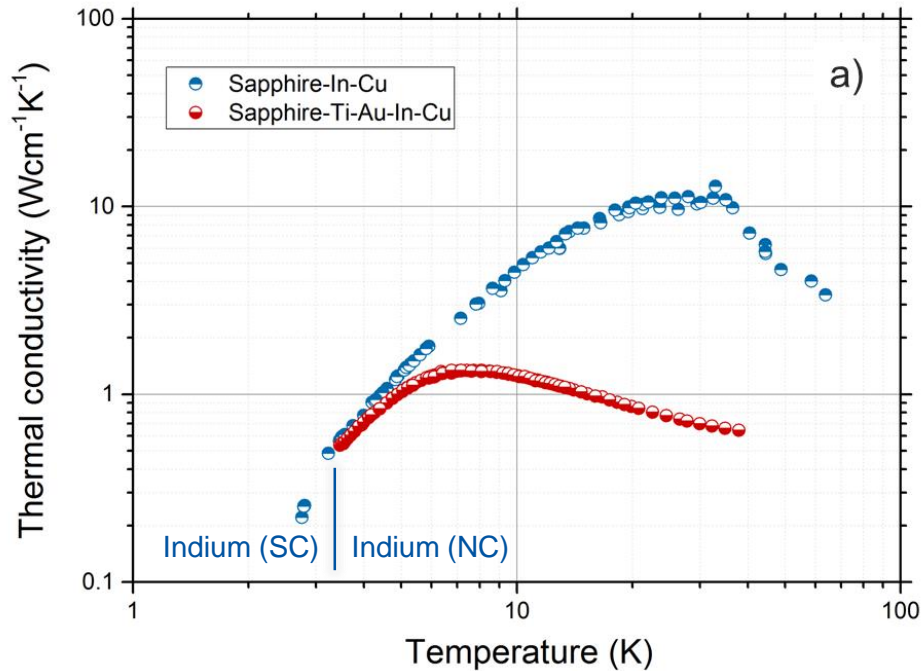
- Pulse 2:** $\kappa = \frac{x_p^2}{4a}$
 - $v = T_1 - T_0$ is the experimental temperature rise
 - Plot $\ln(v\sqrt{t}) = -\frac{x_p^2}{4\kappa} \frac{1}{t} + \ln\left(\frac{\gamma}{\sqrt{\pi\kappa}}\right) = -a \frac{1}{t} + b$
 - diffusivity can be extracted through the slope a



- Step:** $\kappa = 1.38 x_p^2 / \pi^2 t_{1/2}$
 - plot $V = T(x_p, t) / T_{max}$ as a function of $\omega = \frac{\pi^2}{L^2} \kappa t$
 - $t_{1/2}$ is the time when $T(x_p)$ reaches half of the maximum
- 3 ω method and more ...



λ and κ^* of a Cu-In-sapphire and Cu-In-Au-Ti-sapphire sandwich



Modelling of thermal conductivity including the boundary resistances e.g. Cu-In-sapphire:

$$R_i = \frac{d}{\lambda \cdot A} \quad R_s = R_{sap} + R_{In} + R_{Cu} + R_{InSapIn}$$

$$\text{with } R_{InSapIn} = \frac{1}{225} T^{2.5-3.0} \quad \text{in } \frac{m^2}{WK}$$

Gmelin et al., J. Phys. D: Appl. Phys. 32 (1999) R19–R43.

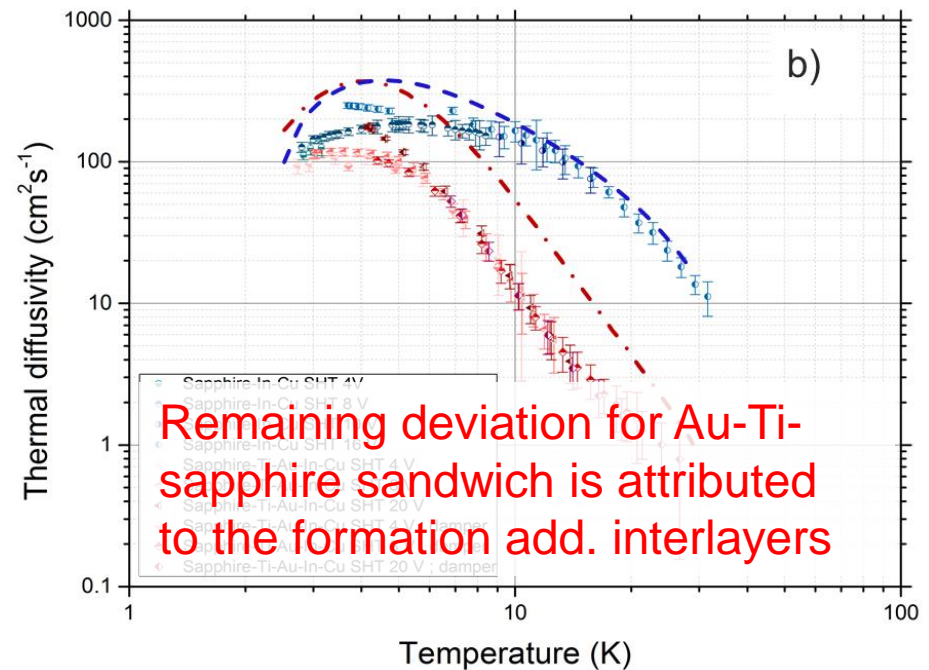
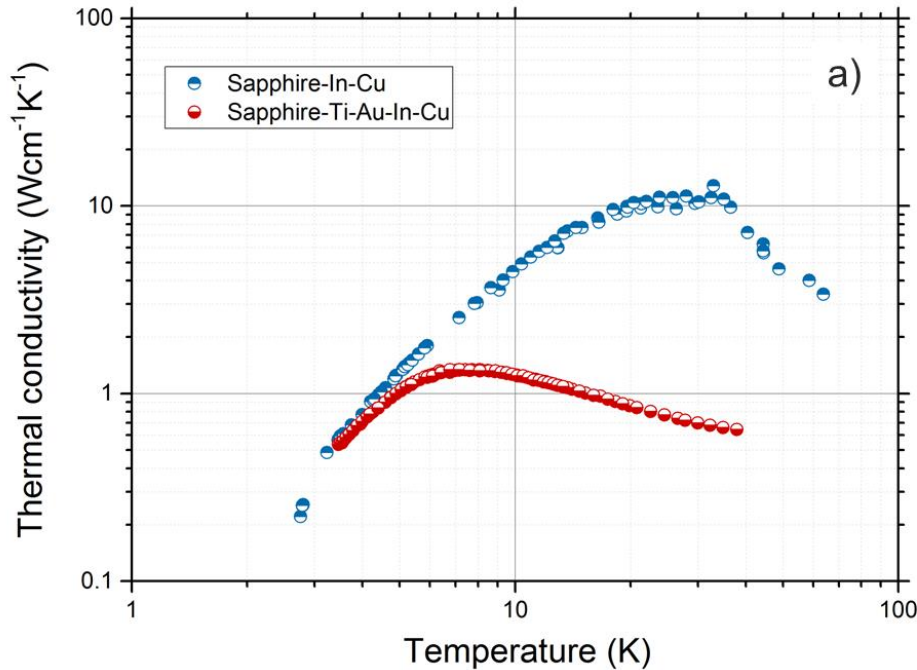
Modelling of diffusivity including λ measured ! of Cu-In-sapphire:

$$c_s \cdot \rho_s = \sum_i \frac{x_i}{d} \cdot c_i \cdot \rho_i$$

$$\kappa^* = \frac{d}{A \cdot R_s \cdot c_s \cdot \rho_s}$$



λ and κ^* of a Cu-In-sapphire and Cu-In-Au-Ti-sapphire sandwich



Modelling of thermal conductivity including the boundary resistances e.g. Cu-In-sapphire:

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Geometry factor: static vs. transient

